FORM PTO - 1449

INFORMATION DISCLOSURE STATEMENT

SP 10 2004

ATTY DOCKET NO.: ASC-049C1

APPLICANT: Fitzgerald

SERIAL NO.: 10/774,890

FILING DATE: February 9, 2004

EXAMINER: Tran, Mai Huong C.

GROUP: 2818

U.S. PATENT DOCUMENTS

EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
42	A1	2001/0003364	06/14/2001	Sugawara et al.			
	A2	2002/0024395	02/28/2002	Akatsuka et al.			
	A3	2002/0043660	04/18/2002	Yamazaki et al.	-		
	A4	2002/0084000	07/04/2002	Fitzgerald			
	A5	2002/0096717	07/25/2002	Chu et al.			
	A6	2002/0100942	08/01/2002	Fitzgerald et al.			
	A7	2002/0123167	09/05/2002	Fitzgerald			
	A8	2002/0123183	09/05/2002	Fitzgerald			
	A9	2002/0125471	09/12/2002	Fitzgerald et al.			
	A10	2002/0168864	11/14/2002	Cheng et al.			
	A11	2003/0003679	01/02/2003	Doyle et al.			
	A12	2003/0013323	01/16/2003	Hammond et al.			
	A13	2003/0034529	02/20/2003	Fitzgerald et al.			
	A14	2003/0057439	03/27/2003	Fitzgerald			
	A15	2003/0102498	06/05/2003	Braithwaite et al.			
	A16	2003/0199126	10/23/2003	Chu et al.			
	A17	2003/0203600	10/30/2003	Chu et al.	-		
	A18	2003/0215990	11/20/2003	Fitzgerald et al.			
	A19	2003/0218189	11/27/2003	Christiansen			
	A20	2003/0227057	12/01/2003	Lochtefeld et al.			
	A21	2004/0005740	01/01/2004	Lochtefeld et al.			
\top	A22	2004/0014304	01/22/2004	Bhattacharyya			
1/	A23	2004/0031979	02/19/2004	Lochtefeld			06/06/2003

FORM	PTO -	1449			ATTY DOCKET NO.: ASC-049C1						
INFOR	MATIC	ON DISCLOSUI	RE STATEM	ENT	APPLICANT: Fit	zgerald					
					SERIAL NO.: 10/774,890						
					FILING DATE: February 9, 2004						
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					GROUP: 2818						
			U.	S. PATE	NT DOCUMENTS	_					
EXAM.		DOCUMENT	DATE	NAME	· · · · · · · · · · · · · · · · · · ·	CLASS	SUB	FILING DATE IF			
INIT.		NUMBER					CLASS	APPROPRIATE			
ux	A24	2004/0041210	03/04/2004	Mouli				09/02/2003			
ĺ	A25	2004/0075149	04/22/2004	Fitzgeral	d et al.			07/23/2003			
	A26	4,010,045	03/01/1977	Ruehrwe	in	٠					
	A27	4,710,788	12/01/1987	Dambkes	et al.						
	A28	4,987,462	01/22/1991	Kim et al							
	A29	4,990,979	02/05/1991	Otto							
1	A30	4,997,776	03/05/1991	Harame e	t al.						
	A31	5,013,681	05/07/1991	Godbey e	et al.						
	A32	5,155,571	10/13/1992	Wang et	al.						
	A33	5,166,084	11/24/1992	Pfiester							
	A34	5,177,583	01/05/1993	Endo et a	ıl.						
	A35	5,202,284	04/13/1993	Kamins e	t al.						
	A36	5,207,864	05/04/1993	Bhat et a	l.						
1	A37	5,208,182	05/04/1993	Narayan	et al.						
	A38	5,212,110	05/18/1993	Pfiester e	t al.						
†	A39	5,221,413	06/22/1993	Brasen et	al.						
1	A40	5,240,876	08/34/1993	Gaul et a	l.						
1-	A41	5,241,197	08/31/1993	Murakam	i et al.						
	A42	5,250,445	10/05/1993	Bean et a	l.						
1	A43	5,285,086	02/08/1994	Fitzgerale	<u> </u>						
1	A44	5,291,439	03/01/1994	Kauffmar	nn et al.						
1/	A45	5,298,452	03/29/1994	Meyerson	1						
1	A46	5,310,451	05/10/1994	Tejwani e	et al.						

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FORM:	PTO -	1449			ATTY DOCKET	NO.: ASC-	049C1			
INFORI	MATI(ON DISCLOSU	RE STATEM	ENT	APPLICANT: F	itzgerald				
					SERIAL NO.: 10/774,890					
					FILING DATE: February 9, 2004					
					EXAMINER: Tran, Mai Huong C.					
					GROUP: 2818					
			U.	S. PATE	NT DOCUMENTS	}				
EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME		CLASS	SUB CLASS	FILING DATE IF APPROPRIATE		
11.4	A47	5,316,958	05/31/1994	Meyerso	n					
1	A48	5,346,848	09/13/1994	Grupen-	Shemansky et al.					
1	A49	5,374,564	12/20/1994	Bruel						
1	A50	5,399,522	03/21/1995	Ohori						
	A51	5,413,679	05/09/1995	Godbey	· · · · · · · · · · · · · · · · · · ·					
	A52	5,424,243	06/13/1995	Takasaki						
	A53	5,426,069	06/20/1995	Selvakur	Selvakumar et al.					
	A54	5,426,316	06/20/1995	Mohamn	nad					
	A55	5,442,205	08/15/1995	Brasen e	t al.					
	A56	5,461,243	10/24/1995	Ek et al.		خسسته				
	A57	5,461,250	10/24/1995	Burghart	z et al.	i				
	A58	5,462,883	10/31/1995	Dennard	et al.					
	A59	5,476,813	12/19/1995	Naruse						
	A60	5,479,033	12/26/1995	Baca et a	ıl.					
	A61	5,484,664	01/16/1996	Kitahara	et al.	-				
	A62	5,523,243	06/04/1996	Mohamn	nad					
	A63	5,523,592	06/04/1996	Nakagaw	va et al.					
	A64	5,534,713	07/09/1996	Ismail et	al.	-				
	A65	5,536,361	07/16/1996	Kondo e	t al.	<u> </u>				
	A66	5,540,785	07/30/1996	Dennard	et al.					
	A67	5,572,043	11/05/1996	Shimizu	et al.					
	A68	5,596,527	01/21/1997	Tomioka	et al.					

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5,617,351

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Bertin et al.

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FORM :	PTO -	1449			ATTY DOCKET	NO.: ASC-	049C1			
INFOR	MATÍC	ON DISCLOSU	RE STATEM	ENT	APPLICANT: F	itzgerald				
					SERIAL NO.: 10/774,890					
					FILING DATE:	February 9,	2004			
					EXAMINER: T	ran, Mai Huo	ng C.			
					GROUP: 2818					
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EXAM.		DOCUMENT	DATE	NAME		CLASS	SUB	FILING DATE IF		
NIT.		NUMBER					CLASS	APPROPRIATE		
UK	A70	5,630,905	05/20/1997	Lynch et	al.					
)	A71	5,659,187	08/19/1997	Legoues	et al.					
	A72	5,683,934	11/04/1997	Candelar	ia					
	A73	5,698,869	12/16/1997	Yoshimi	et al.	ن -				
	A74	5,714,777	02/03/1998	Ismail et	al.					
1	A75	5,728,623	03/17/1998	Mori						
	A76	5,739,567	04/14/1998	Wong						
+	A77	5,759,898	06/02/1998	Ek et al.						
	A78	5,777,347	07/07/1998	Bartelink						
	A79	5,786,612	07/28/1998	Otani et d	ıl.					
	A80	5,786,614	07/28/1998	Chuang e	et al.					
	A81	5,792,679	08/11/1998	Nakato						
	A82	5,808,344	09/15/1998	Ismail et	al.					
	A83	5,847,419	12/08/1998	Imai et a	l.					
	A84	5,877,070	03/02/1999	Goesele 6	et al.					
+	A85	5,891,769	04/06/1999	Liaw et a	ıl.					
+	A86	5,906,708	05/25/1999	Robinsor	et al.					
	A87	5,906,951	05/25/1999	Chu et al						
	A88	5,912,479	06/15/1999	Mori et a	il.					
+-	A89	5,943,560	08/24/1999	Chang et	al.					
+-	A90	5,963,817	10/05/1999	Chu et al						
	A91	5,966,622	10/12/1999	Levine et	al.					
+-	A92	5,998,807	12/07/1999	Lustig et	al.					

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FORM 1	PTO - 1	1449			ATTY DOCKET	NO.: ASC	049C1				
NFOR	MATIO	N DISCLOSU	RE STATEM	ENT	APPLICANT: Fit	zgerald .					
					SERIAL NO.: 10/	774,890					
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					EXAMINER: Tran, Mai Huong C.						
					GROUP: 2818						
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EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME		CLASS	SUB CLASS	FILING DATE IF APPROPRIATE			
asto	A93	6,013,134	01/11/2000	Chu et al	7.						
	A94	6,030,887	02/29/2000	Desai et	al.	-					
	A95	6,030,889	02/29/2000	Aulicino	et al.						
	A96	6,033,974	03/07/2000	Henley e	t al.	-					
	A97	6,033,995	03/07/2000	Muller							
	A98	6,058,044	05/02/2000	Sugiura e	et al.						
	A99	6,059,895	05/09/2000	Chu et al	<u> </u>	e					
	A100	6,074,919	06/13/2000	Gardner	et al.						
1 .	A101	6,096,590	08/01/2000	Chan et a	ıl.						
	A102	6,103,559	08/15/2000	Gardner	et al.						
	A103	6,107,653	08/22/2000	Fitzgeral	d						
	A104	6,111,267	08/29/2000	Fischer e	t al.						
	A105	6,117,750	09/12/2000	Bensahel	et al.						
	A106	6,130,453	10/10/2000	Mei et al							
	A107	6,133,799	10/17/2000	Favors et	t al.						
	A108	6,140,687	10/31/2000	Shimom	ıra et al.						
	A109	6,143,636	11/07/2000	Forbes et	t al.						
	A110	6,153,495	11/28/2000	Kub et a	1.						
	Alli	6,154,475	11/28/2000	Soref et a	al.						
	A112	6,160,303	12/12/2000	Fattarusc)						
	A113	6,162,688	12/19/2000	Gardner	et al.						
17	A114	6,184,111	02/06/2001	Henley e	t al.	<u>ت</u>					

EXAMINER / CALCULOW DATE CONSIDERED 09/22/0

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6,191,007

FORM 1	PTO - 1	449			ATTY DOCKET NO.: ASC-049C1						
INFORM	MATIO	N DISCLOSUI	RE STATEM	ENT	APPLICANT: Fitzgerald						
					SERIAL NO.: 10	/774,890					
					FILING DATE: February 9, 2004						
					EXAMINER: Tran, Mai Huong C.						
					GROUP: 2818						
·			U.	S. PATE	NT DOCUMENTS						
EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME		CLASS	SUB CLASS	FILING DATE IF APPROPRIATE			
ut	A116	6,191,432	02/20/2001	Sugiyam	a et al.						
	A117	6,194,722	02/27/2001	Fiorini et	al.						
	A118	6,204,529	03/20/2001	Lung et a	ıl.						
	A119	6,207,977	03/27/2001	Augusto	· · · · · · · · · · · · · · · · · · ·	 					
	A120	6,210,988	04/03/2001	Howe et	al.						
	A121	6,218,677	04/17/2001	Brockaer	t						
	A122	6,232,138	05/15/2001	Fitzgeral	d et al.	T					
	A123	6,235,567	05/22/2001	Huang							
	A124	6,242,324	06/05/2001	Kub et al							
	A125	6,249,022	06/19/2001	Lin et al.							
	A126	6,251,755	06/26/2001	Furukawa	a et al.						
	A127	6,261,929	07/17/2001	Gehrke e	t al.						
	A128	6,266,278	07/24/2001	Harari et	al.						
	A129	6,271,551	08/07/2001	Schmitz	et al.						
	A130	6,271,726	08/07/2001	Fransis e	t al.						
	A131	6,291,321	09/18/2001	Fitzgeral	d						
	A132	6,313,016	11/06/2001	Kibbel et	al.						
	A133	6,316,301	11/13/2001	Kant							
	A134	6,323,108	11/27/2001	Kub et al							
	A135	6,329,063	12/11/2001	Lo et al.							
	A136	6,335,546	01/01/2002	Tsuda et	al.						
	A137	6,339,232	01/15/2002	Takagi							
$\sqrt{}$	A138	6,350,993	02/26/2002	Chu et al							
EXAMII	NER	11/1	alle	100	DATE CONSID	ERED	09/	22/04			

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FORM	PTO - 1	1449			ATTY DOCKET	NO.: ASC	-049C1			
INFOR	MATIC	N DISCLOSU	RE STATEM	ENT	APPLICANT: Fit	zgerald				
					SERIAL NO.: 10/774,890					
					FILING DATE: February 9, 2004					
					EXAMINER: Tran, Mai Huong C.					
					GROUP: 2818					
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EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME		CLASS	SUB CLASS	FILING DATE IF APPROPRIATE		
Mit	A139	6,352,909	03/05/2002	Usenko						
	A140	6,368,733	. 04/09/2002	Nishinag	8					
	A141	6,372,356	04/16/2002	Thornton	et al.		ļ			
	A142	6,372,593	04/16/2002	Hattori e	et al.					
	A143	6,399,970	06/04/2002	Kubo et e	al.					
	A144	6,403,975	06/11/2002	Brunner	et al.	c				
	A145	6,407,406	06/18/2002	Tezuka						
	A146	6,420,937	07/16/2002	Akatsuka	et al.					
	A147	6,425,951	07/30/2002	Chu et al	1.					
	A148	6,429,061	08/06/2002	Rim						
	A149	6,521,041	02/18/2003	Wu et al.						
	A150	6,524,935	02/25/2003	Canaperi	et al.					
	A151	6,555,839	04/29/2003	Fitzgeral	d					
	A152	6,573,126	06/03/2003	Cheng et	al.					
	A153	6,583,015	06/24/2003	Fitzgeral	d et al.					
	A154	6,593,191	07/15/2003	Fitzgeral	d					
	A155	6,593,641	07/15/2003	Fitzgeral	d	9				
	A156	6,602,613	08/05/2003	Fitzgeral	d					
	A157	6,603,156	08/05/2003	Rim						
	A158	6,646,322	11/11/2003	Fitzgeral						
	A159	6,649,480	11/18/2003	Fitzgeral						
	A160	6,677,192	01/13/2004	Fitzgeral						
	A161	6,703,144	03/09/2004	Fitzgeral	d			03/18/2003		

03/09/2004 Fitzgerald EXAMINER DATE CONSIDERED

FORM	1 РТО	- 1	1449					ATTY DOCKET NO.: ASC-049C1					
INFO	RMAT	°IO	N DISCLO	SUR	E STAT	'EM	ENT	APPLIC	CANT: Fi	tzgerald			
								SERIAI	NO.: 10	/774,890			
								FILING	DATE:	February 9	, 2004		
ı								EXAM	NER: Tr	an, Mai Hu	iong C.		
								GROUE	P: 2818				
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EXAM. INIT.			DOCUMEN' NUMBER	r	DATE		NAME			CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
NH	A16	52	6,703,688		03/09/2	004	Fitzgeral	d				07/16/2001	
7-18	A16	53	6,709,903		03/23/2	004	Christian	isen			+	04/30/2003	
	A16	54	6,713,326		03/30/2	004	Cheng e	t al.				03/04/2003	
	A16	55	6,723,661		04/20/2	004	Fitzgeral	d			-	07/16/2001	
	A16	66	6,724,008		04/20/2	004	Fitzgeral	d		_		07/16/2001	
	A16	57	6,730,551		05/04/2	004	Lee et al					08/02/2002	
\mathcal{I}	A16	8	6,737,670		05/18/2	004	Cheng et	al.				03/07/2003	
	A16	9	6,750,130		06/15/2	004	Fitzgeral	d		1		01/07/2001	
					F	ORE	IGN PA	TENT DO	CUMEN	ΓS		-	
EXAM .INIT.		-	OCUMENT JMBER	DA	ΓE	CO	UNTRY DE	CLASS	SUB CLASS	FILING DATE	ABSTRACT	ENGLISH LANG (Y/N)	
UH	BI	41	01 167	07/	23/1992	DE					N	Y (Abstract only)	
1	B2	0:	514 018	11/	19/1992	EP					N	Y	
	В3		587 520		16/1994	EP					_N	Y	
	B4	0 (583 522	11/	22/1995	EP					N	Y	
	B5		328 296		11/1998	EP					_N	Υ	
	В6		329 908		18/1998	EP					N	Y	
	В7		338 858		29/1998	EP					Ŋ	Y (Abstract only)	
<u> </u>	B8		020 900		19/2000	EP		<u></u>			N	Y	
	В9		174 928		23/2002	EP		-			N	Y	
	B10		701 599		01/1993	FR					Y	Y	
	B11		342 777		19/2000	GB					N	Υ.	
/	B12		/141116		28/1986	JP					N	Y (Abstract only)	
V	B13	2/2	210816		22/1990	JP	/				.N	Y (Abstract only)	
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FORM	PTO	- 1449					ATTY D	OCKET N	IO.: ASC	-049Cl		
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							SERIAL	NO.: 10/	774,890			
							FILING	DATE: F	ebruary 9,	2004		
							EXAMI	NER: Trai	ı, Mai Hu	ong C.		
							GROUP:					
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EXAM. INIT.		DOCUMEN NUMBER	Т	DATE		NAME		-	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
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EXAM . INIT.		DOCUMENT NUMBER	DA	TE	co	UNTRY DE	CLASS	SUB CLASS	FILING DATE	ABSTRAC ONLY	ENGLISH LAN	١G
UH	B14	3/036717	02/	18/1991	JР					N	Y	
	B15	4-307974	10/	30/1992	JP					N	Y (Abstract on	ly)
	B16	5-166724	07/	23/1993	JP					N	Y (Abstract on	ly)
	B17	6-177046	06/	24/1994	JP					_N	Y (Abstract on	ly)
	B18	6-244112	09/	02/1994	JP					Y	Y	
	B19	6-252046	09/	09/1994	JP					Y	Y	
	B20	7-094420	04/	07/1995	JР					N	Y (Abstract on	ly)
	B21	7-106446	04/	21/1995	JP					Y	Y	_
	B22	7-240372	09/	12/1995	JP					Y	Y	
	B23	10-270685	10/	09/1998	JР					N	Y	
	B24	11-233744	08/	27/1999	JР					N	Y (Abstract on	ly)
	B25		01/	21/2000	JP					N	Y	
	B26	2000-031491	01/	28/2000	JP					Y	Y	
	B27	2001-319935	11/	16/2001	JP		-			N	Y	
	B28	2002-076334	03/	15/2002	JP					N	Y	
	B29	2002-164520	06/	07/2002	JP					N	Υ	
	B30	2002-289533	10/	04/2002	JP					N	Y	
	B31	98/59365		30/1998	WC					N	Υ	
	B32	99/53539		21/1999	WC					N	Υ	
$\sqrt{}$	B33	00/48239	08/	17/2000	WC)				N	Y	
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FORM	PTO -	1449			ATTY DO	CKET N	O.: ASC-	049C1			
INFOR	MATI	ON DISCLOSU	JRE STATE	MENT	APPLICA	NT: Fitz	gerald				
					SERIAL NO.: 10/774,890						
					FILING DA	ATE: Fe	bruary 9, 2	2004			
					EXAMINE	R: Tran	, Mai Huo	ng C.			
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EXAM.		DOCUMENT	DATE	NAME			CLASS	SUB		G DATE IF	
INIT.		NUMBER						CLASS	APPR	OPRIATE	
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			FO	REIGN PAT	TENT DOCU	JMENTS	5				
EXAM. INIT.		DOCUMENT NUMBER	DATE	COUNTRY CODE	CLASS	SUB CLASS	FILING DATE	ABSTI		ENGLISH LANG (Y/N)	
UH	B34	00/54338	09/14/2000	wo				N		Y	
	B35	01/22482	03/29/2001	wo				N		Y	
	B36	01/54202	07/26/2001	wo				_ N		Y	
l	B37	01/93338	12/06/2001	wo	-			_ N		Y	
	B38	01/99169	12/27/2001	wo				N		Y	
	B39	02/13262	02/14/2002	wo				_ N		Y	
	B40	02/15244	02/21/2002	wo				N		Y	
	B41	02/27783	04/04/2002	wo				N		Y	
	B42	02/47168	06/13/2002	wo				N		Y	
	B43	02/071488	09/12/2002	wo				N		Y	
	B44	02/071491	09/12/2002	wo				N		Y	
	B45	02/071495	09/12/2002	wo				N		Y	
	B46	02/082514	10/17/2002	WO				_ N		Y	
	B47	04/006311	01/15/2004	wo				N		Y	
\sqrt{V}	B48	04/006327	01/15/2004	WO				_ N		Y	
			OTHER	R ART, JOU	IRNAL ART	icles,	ETC.				
EXAM. INIT.	отн	ER DOCUMENT	rs: (Including	Author, Tit	le, Date, Rele	vant Pag	es, Place of	l Publication	on)		
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